

Optimal architecture for ultralow noise graphene transistors at room temperature

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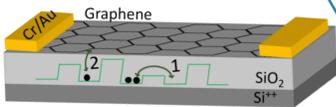


1. Motivation

❖ Dominant sources of 1/f noise in graphene FETs:

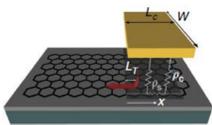
• **Mobility fluctuation (1):**
Hooge Model

$$\frac{S_V(f)}{V^2} = \frac{\gamma_H V^2}{n A f}$$



• **Charge density fluctuations (2):**
McWhorter Model

$$\frac{S_V(f)}{V^2} = \frac{6.2e^2 K_B}{A k C^2 f} T D_{it} \frac{g_m^2}{I_D^2}$$



• **Contact noise^[2]:**

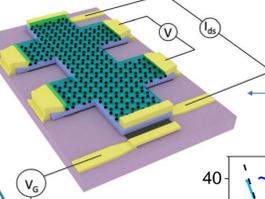
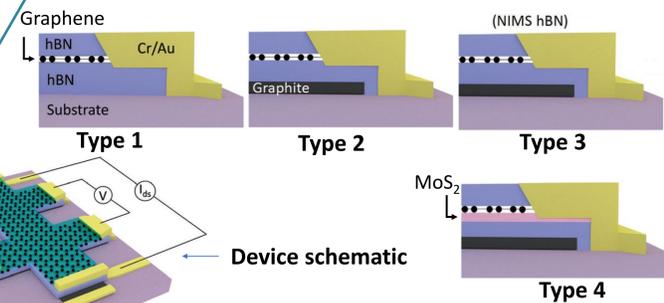
$$\langle (\Delta R c)^2 \rangle \propto R c^4$$

❖ Limited efforts exist to identify optimal architecture that minimizes noise in graphene FETs.

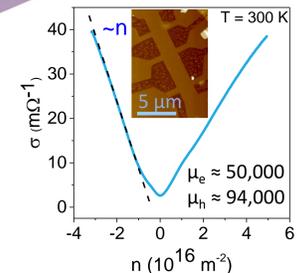
2. Introduction

- We study 1/f noise in graphene in various architectures to get ultralow noise graphene transistors.
- Noise not only limited to contact noise, but also to hBN trap states.
- MoS₂ underneath graphene further reduces the noise by screening the traps of hBN.
- Applications: high-sensitive sensors, optoelectronics, etc.

3. Various architectures and device characteristics



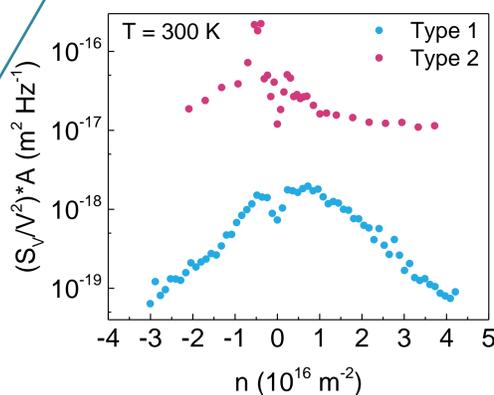
Device schematic



- AFM indicates that channel is free of wrinkles/bubbles/residues.
- Pristine channel of graphene reflects in mobility as well.

μ is in cm²/Vs

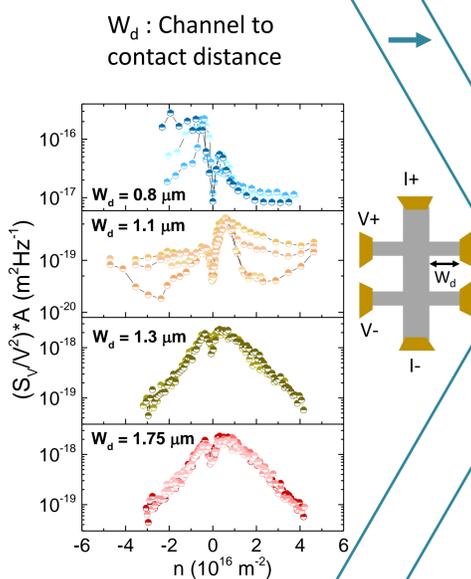
5. Graphite back gate



- Even on thick hBN, proximity effects of SiO₂ leads to fluctuations in graphene channel.
- Graphite back gate screens the potential fluctuations from SiO₂.

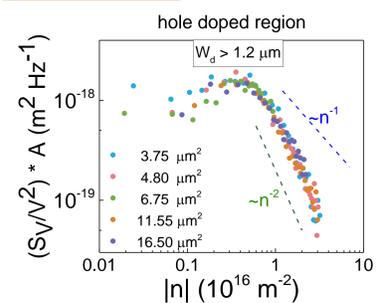
4. Contact noise elimination

- For $W_d < 1.2 \mu\text{m}$, contact noise dominates over channel noise.
- Non-local effects due to finite size of voltage probes can lead to fluctuations at the contacts.
- For $W_d > 1.2 \mu\text{m}$, normalized noise scales with area.
- Indicates, channel is the origin of noise.



6. hBN traps

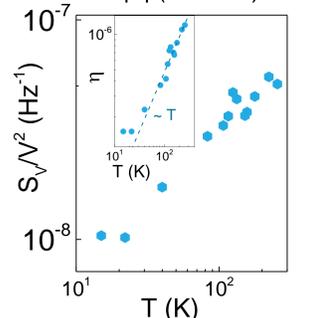
Normalised noise $\propto n^{-2}$
Implies, number density fluctuations.



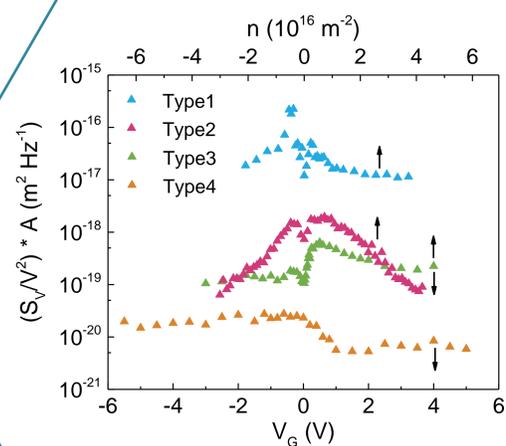
$$\eta = \frac{S_V}{V^2} \frac{1}{\frac{g_m^2}{I_D^2}}, \quad \eta = K * T D_{it}$$

$$D_{it} \approx 2.7 * 10^{15} \text{ eV}^{-1} \text{ cm}^{-3}$$

Value of D_{it} agrees with reported trap density of hBN^[3].



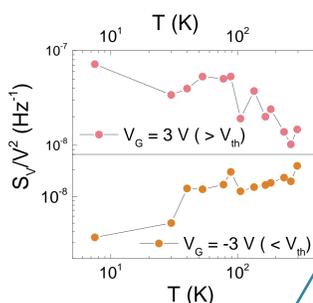
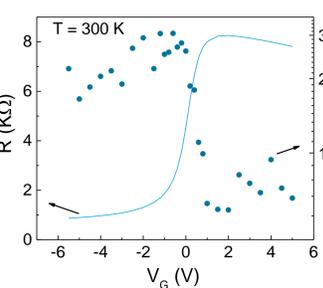
8. Optimal architecture



Type 4 architecture leads to lowest noise after removing contribution from contact noise and effects of fluctuations from bottom hBN traps.

7. MoS₂ as a screening layer

- As soon as MoS₂ is turning ON ($V_G > V_{th}$), noise reduces.
- MoS₂ is acting as a screening layer for fluctuations from hBN traps.

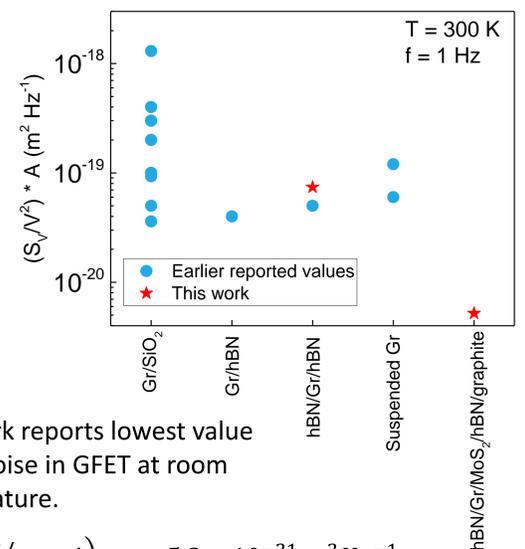


- For $V_G > V_{th}$, screening is increasing (hence noise reduces) with increasing temperature, due to rise in carrier density in MoS₂.

10. Conclusion

- Hall bar geometry, graphite back gate, BN encapsulation and MoS₂ underneath, make graphene transistors with ultra low noise.
- Noise may further be reduced by introducing MoS₂ on top.
- Low noise Gr/MoS₂ hybrid will be crucial in its applications as high-sensitivity optoelectronic element.

9. Comparison with earlier reports



Our work reports lowest value of 1/f noise in GFET at room temperature.

$$\left(\frac{S_V}{V^2} * A\right)_{min} \approx 5.2 * 10^{-21} \text{ m}^2 \text{ Hz}^{-1}$$

$$\gamma_{H,min} \approx 5.2 * 10^{-6}$$

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